



RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2125

00862.022239 (862.C2239)

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
SHIGEYUKI UZAWA, ET AL.)
Application No.: 09/864,309)
Filed: May 25, 2001)
For: EXPOSURE APPARATUS, COATING/DEVELOPING)
SYSTEM, DEVICE MANUFACTURING SYSTEM,)
DEVICE MANUFACTURING METHOD,)
SEMICONDUCTOR MANUFACTURING FACTORY,)
AND EXPOSURE APPARATUS MAINTENANCE)
METHOD)

: Examiner: Ryan A. Jarrett
: Group Art Unit: 2125
: Confirmation No.: 2803
: March 22, 2005

Do not enter
4/2/05
BJ

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

Introductory Comments

In response to the final Official Action dated December 22, 2004, please amend
the above-identified application as follows, pursuant to 37 C.F.R. § 1.116: